

Docket No.: S1459.70088US00  
(PATENT)


**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Masashi Enomoto et al.  
Serial No.: 10/822,556  
Confirmation No.: 2616  
Filed: April 12, 2004  
For: PHOTOELECTRIC CONVERSION DEVICE FABRICATION  
METHOD, PHOTOELECTRIC CONVERSION DEVICE,  
ELECTRONIC APPARATUS MANUFACTURING METHOD,  
ELECTRONIC APPARATUS, METAL FILM FORMATION  
METHOD AND LAYER STRUCTURE AND SEMICONDUCTOR  
FINE PARTICLE LAYER AND LAYER STRUCTURE  
Examiner: G. Mowla  
Art Unit: 1795

**Certificate of Electronic Filing Under 37 CFR 1.8**

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being transmitted via the Office electronic filing system in accordance with § 1.6(a)(4).

Dated: October 17, 2008

  
Paula K. Fairweather

**AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Office Action dated September 2, 2008, finally rejecting claims 1-31, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 22 of this paper.